

INDUCTIVELY COUPLED RF PLASMA REACTOR AND  
PLASMA CHAMBER ENCLOSURE STRUCTURE THEREFOR  
INVENTOR: COLLINS, et al. DKT: 306 D11

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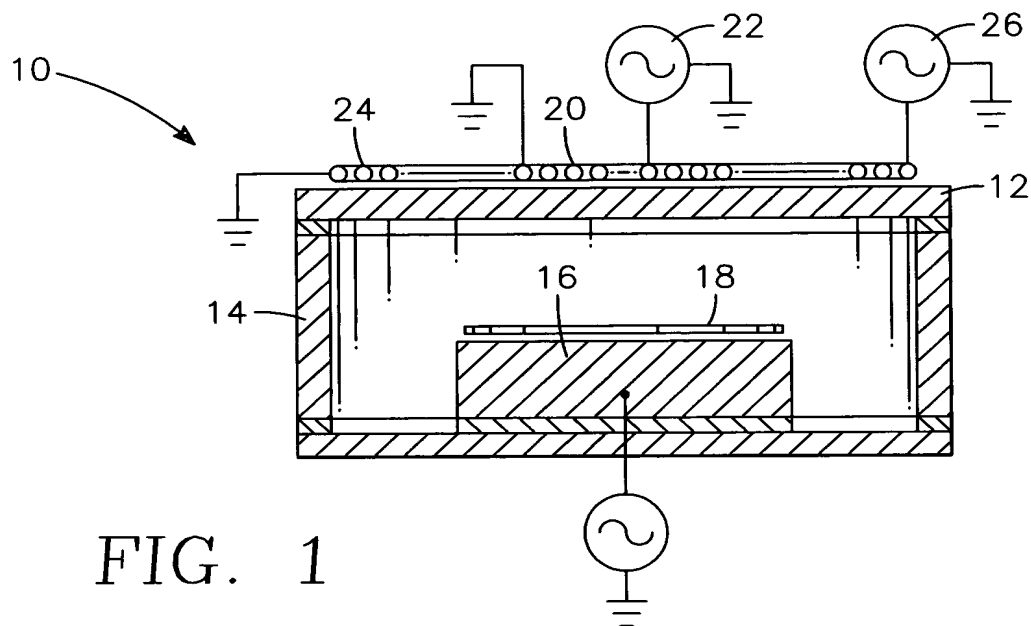


FIG. 1

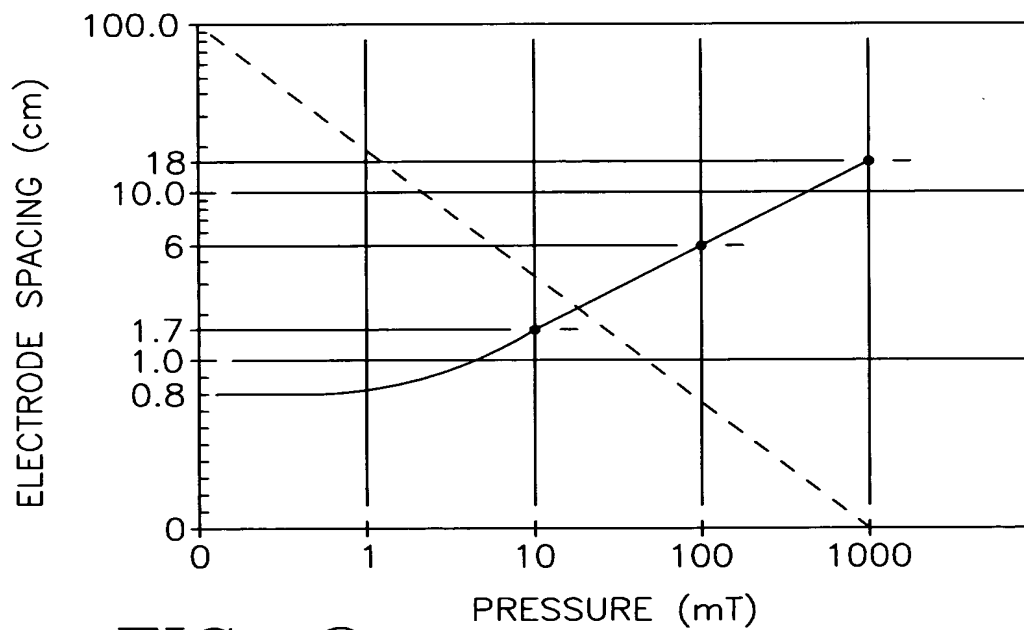
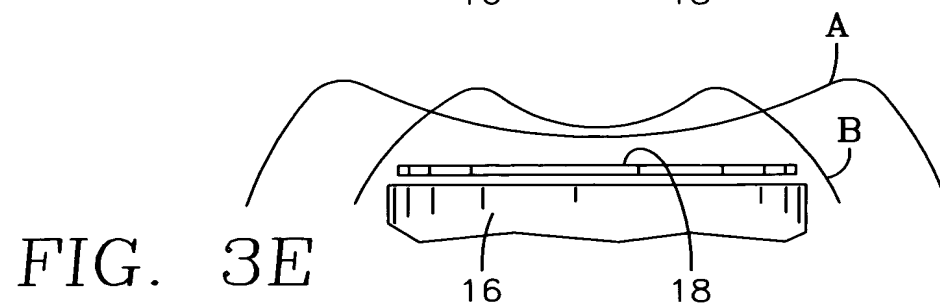
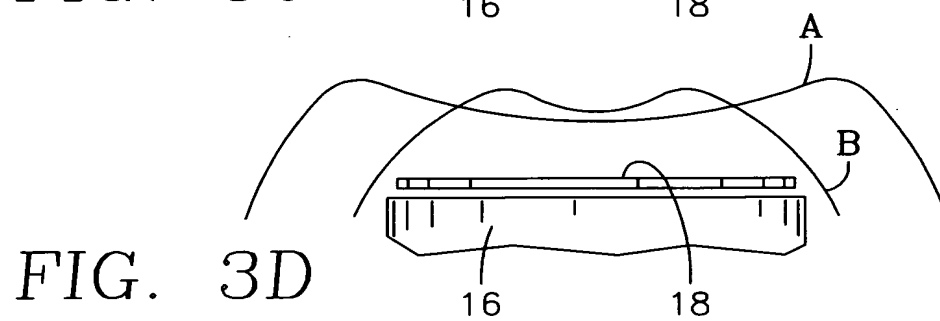
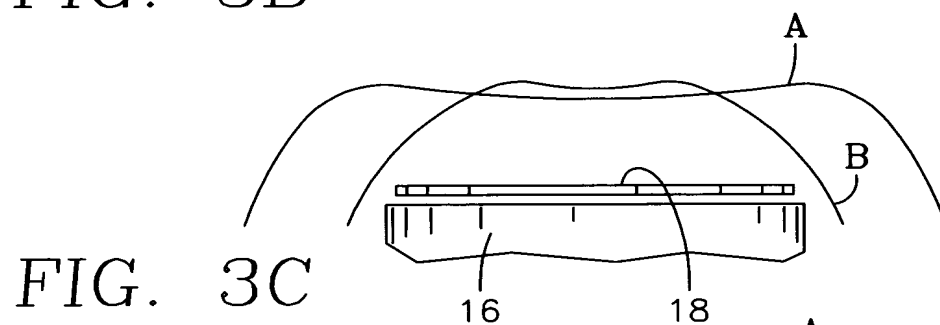
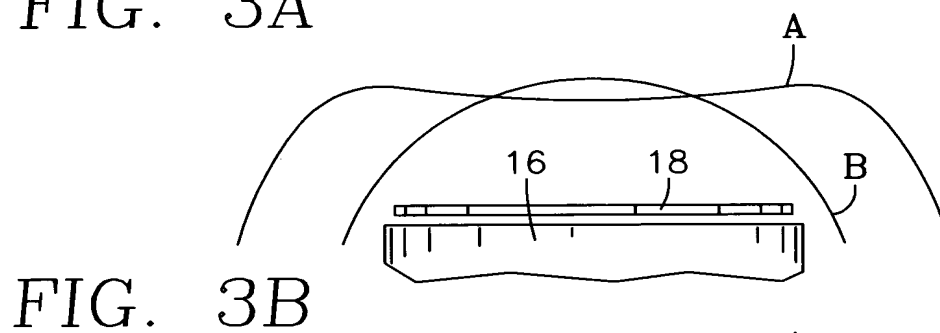
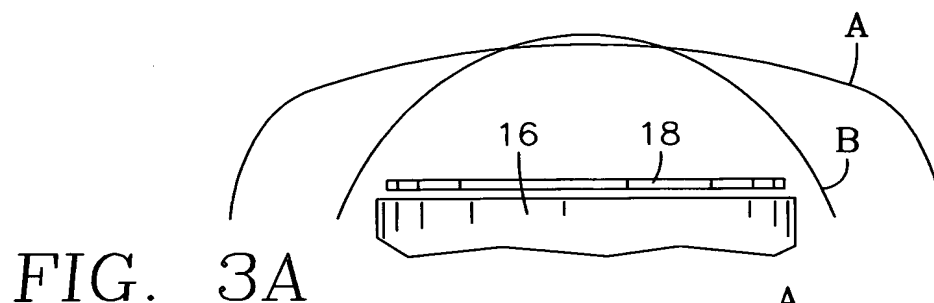
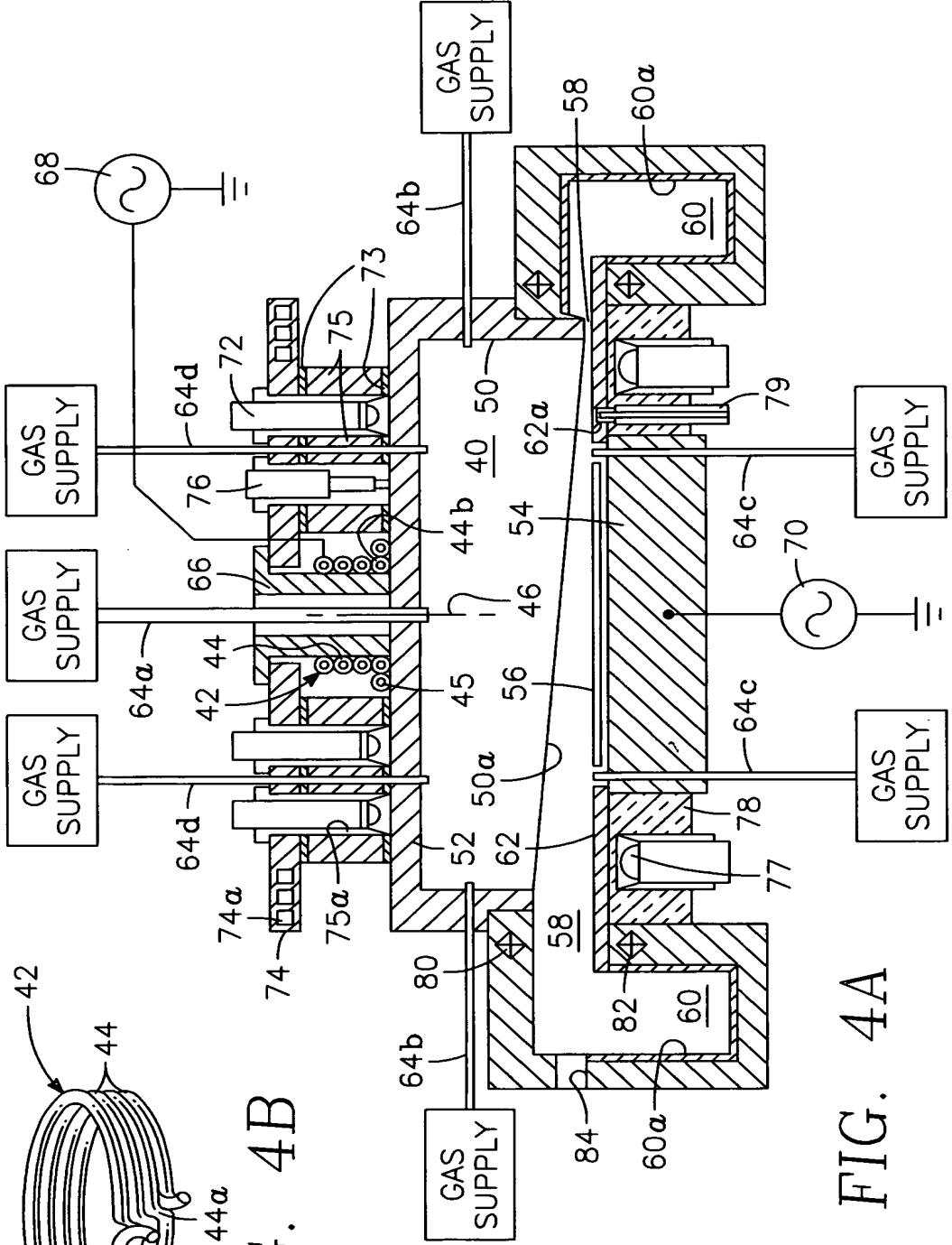
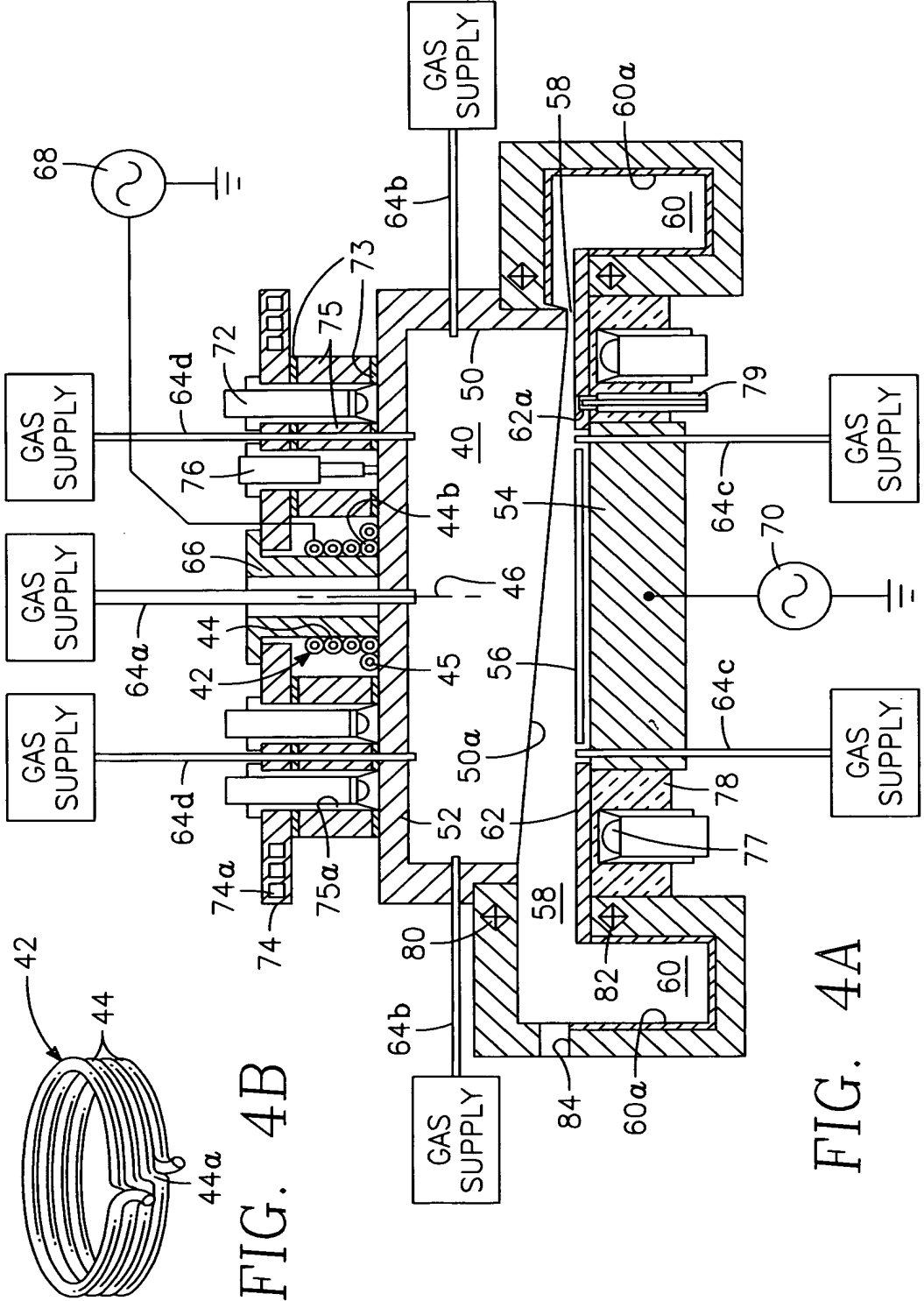


FIG. 2

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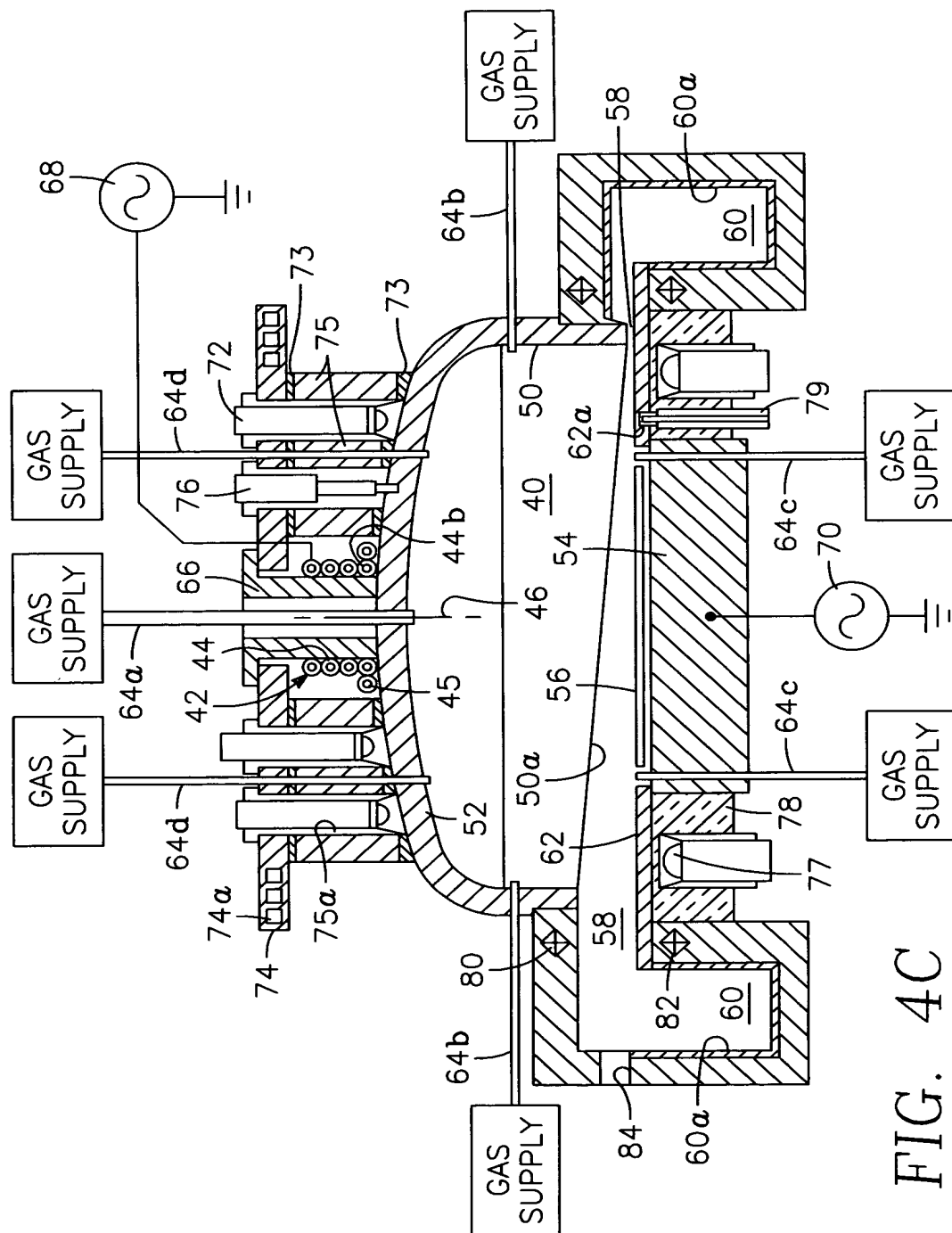


FIG. 4C

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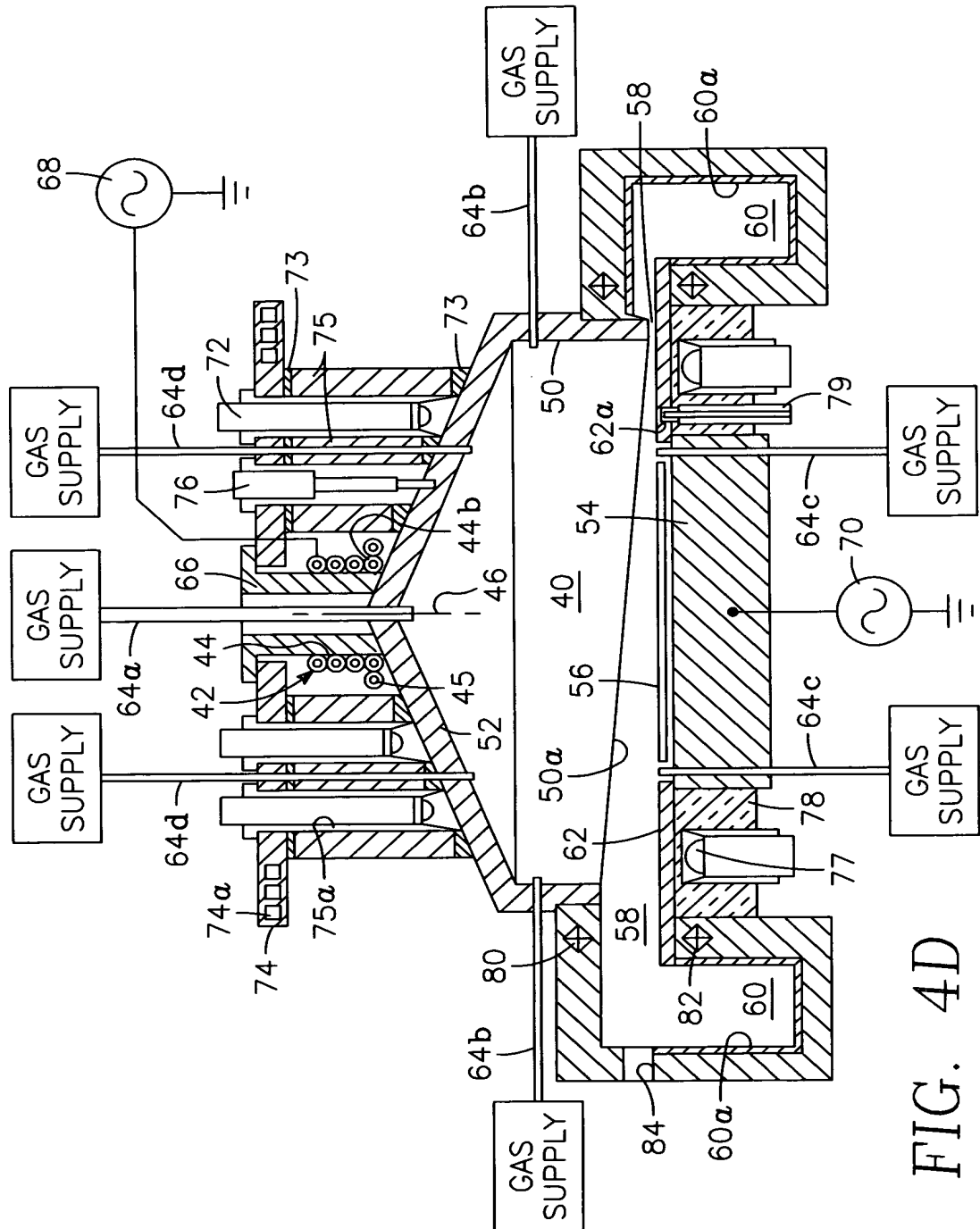


FIG. 4D

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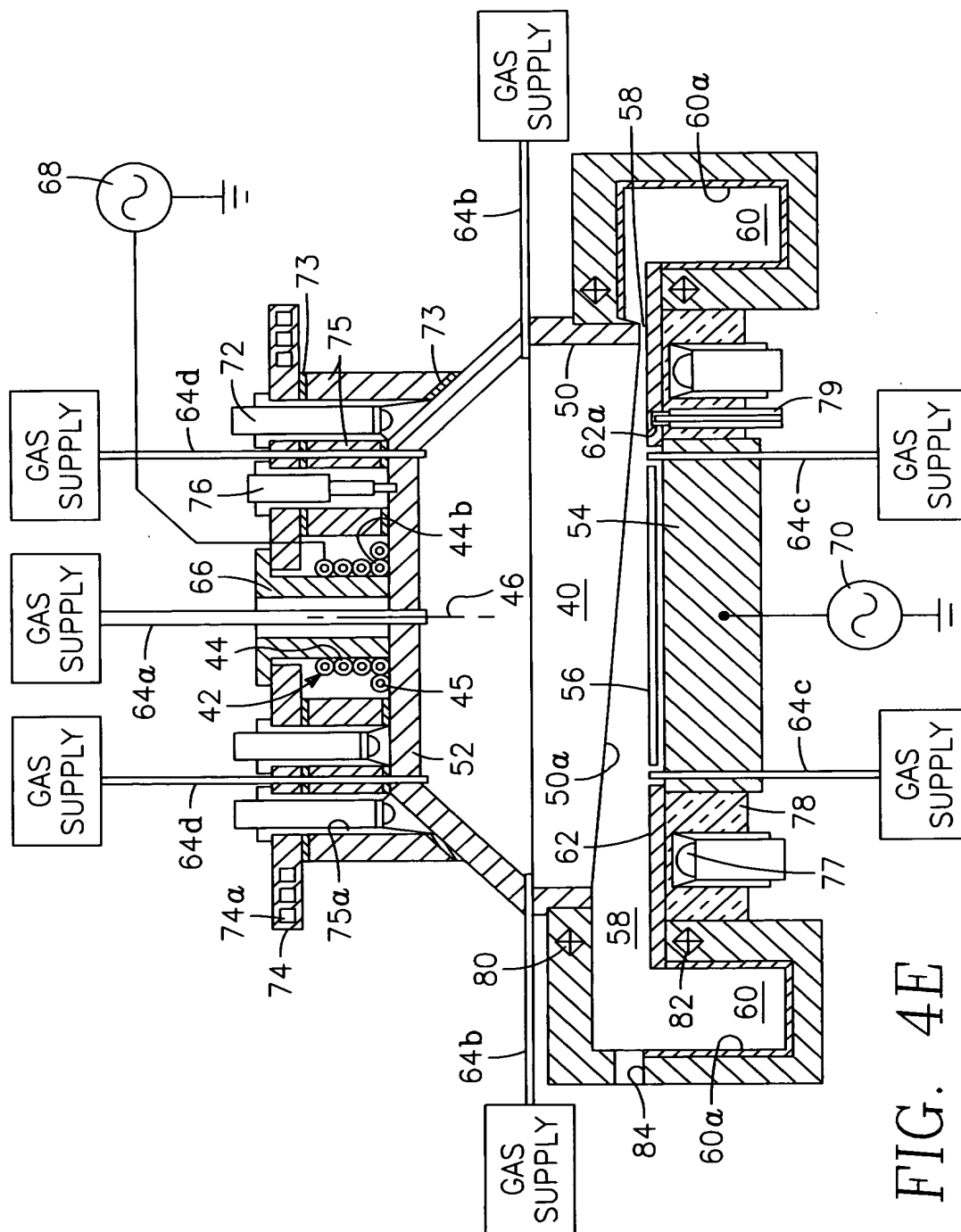


FIG. 4E

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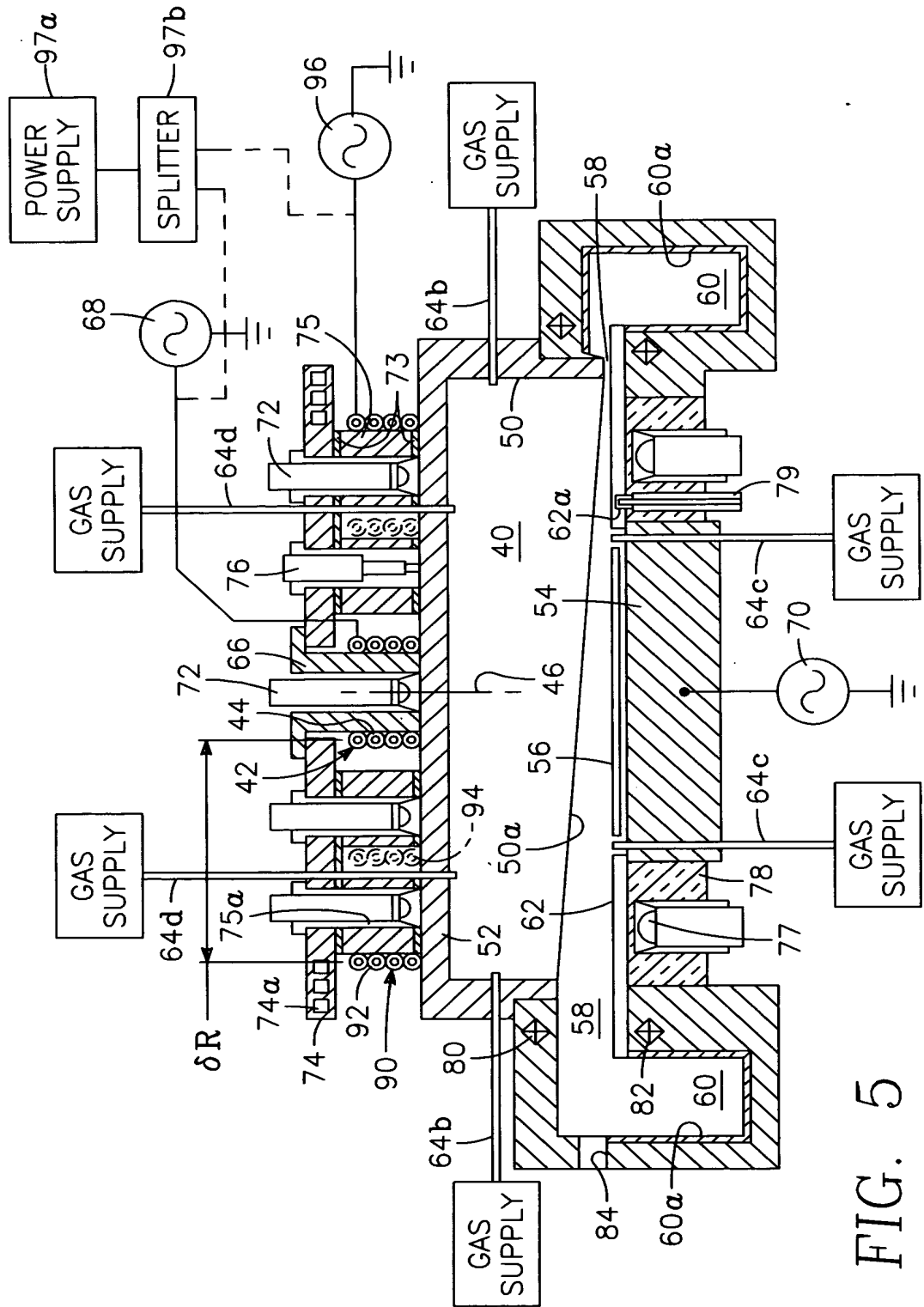


FIG. 5

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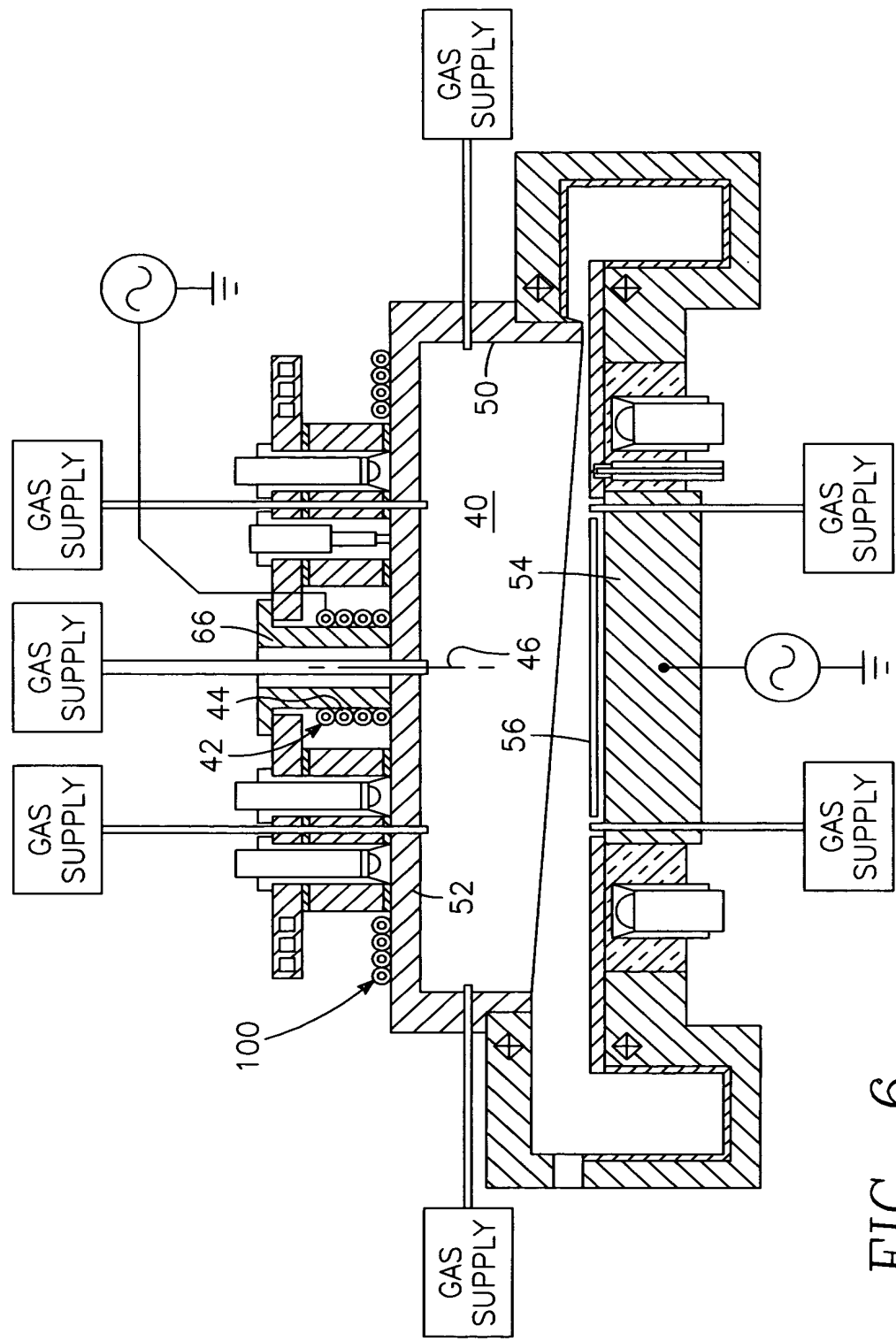


FIG. 6



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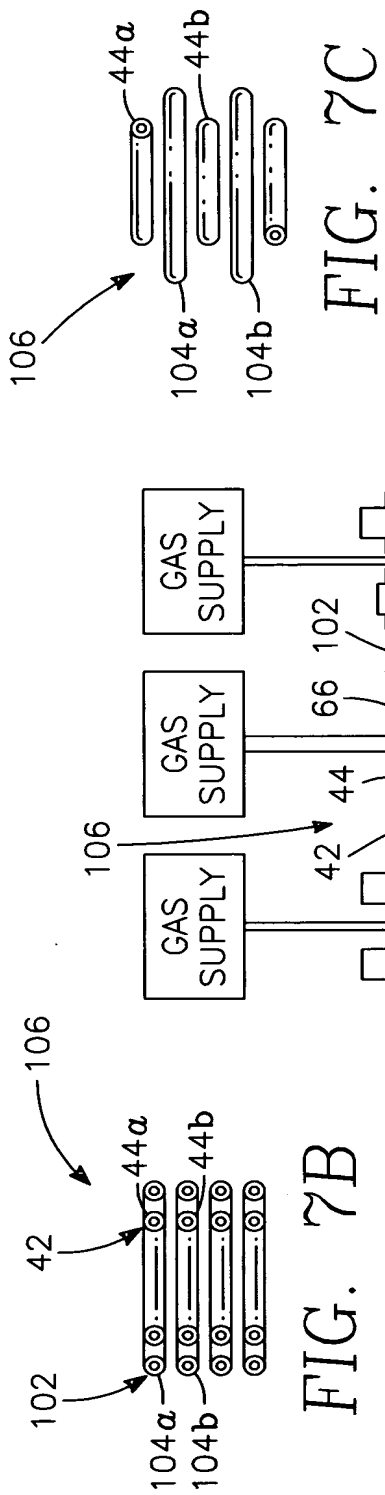


FIG. 7C

FIG. 7B

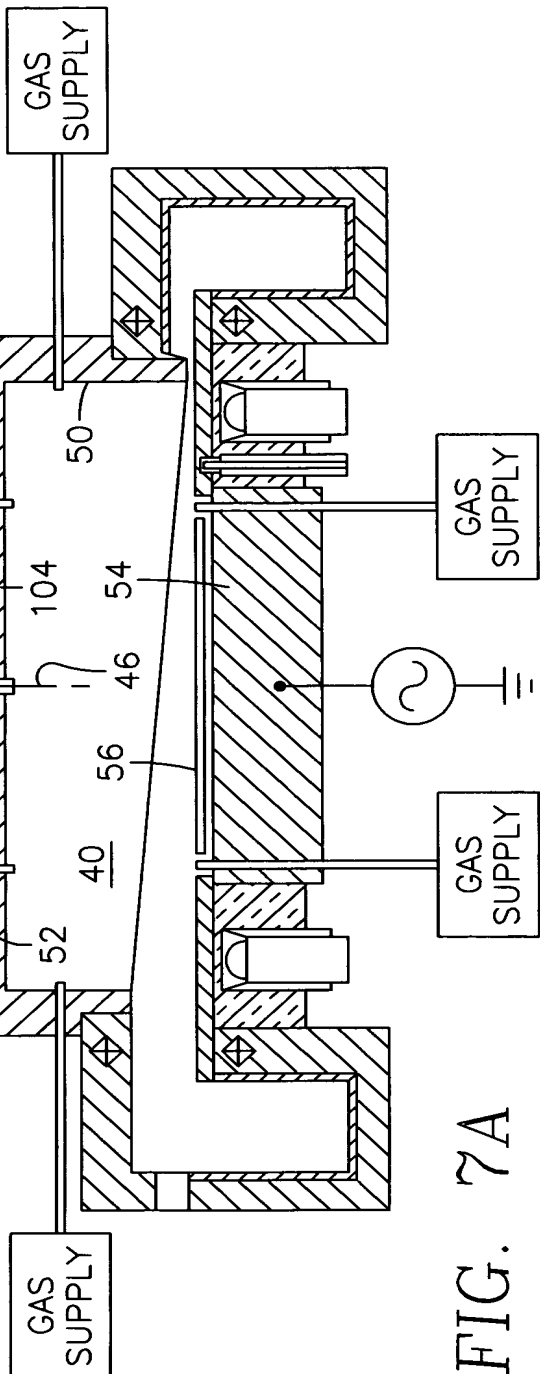


FIG. 7A

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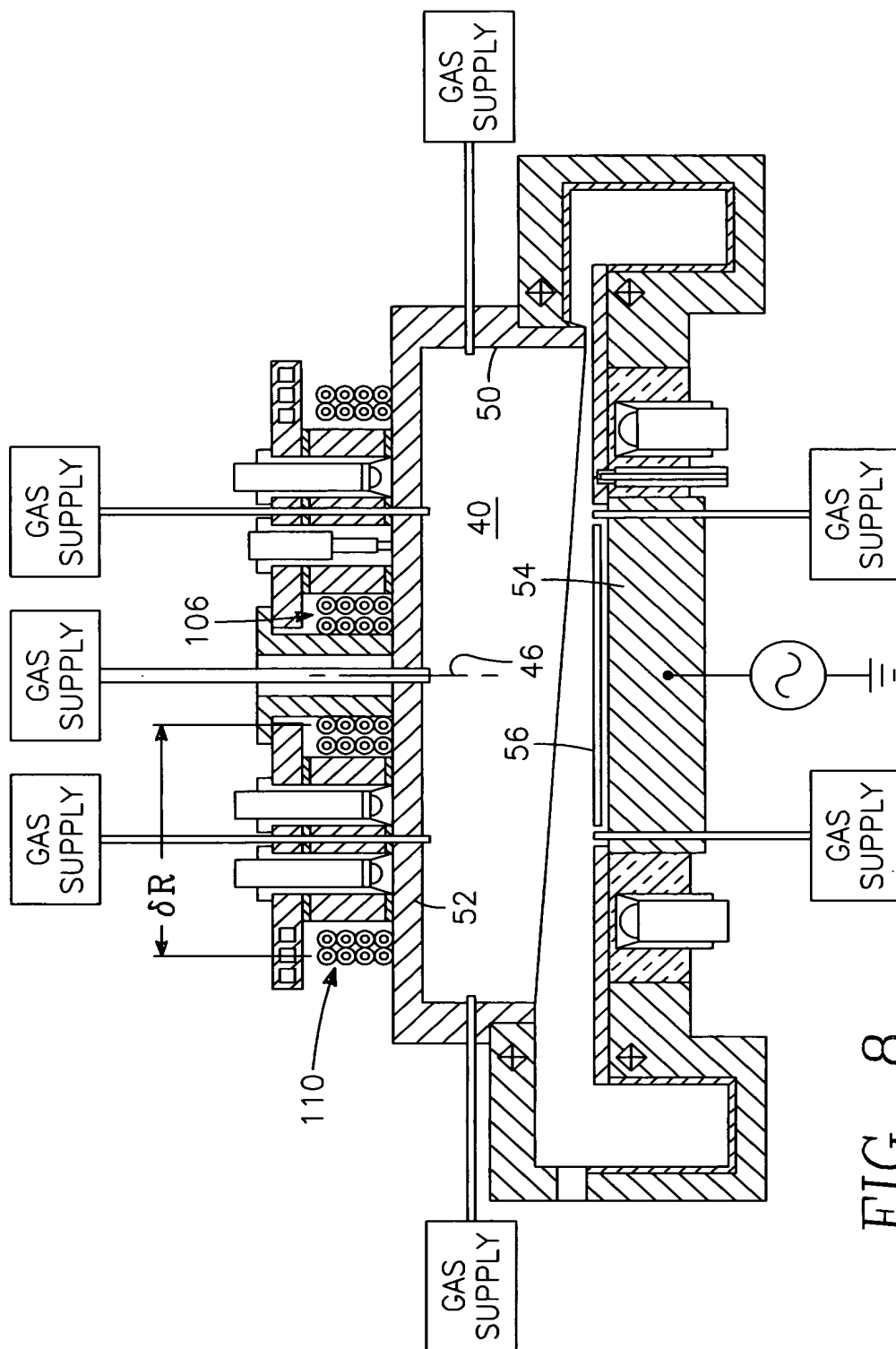


FIG. 8

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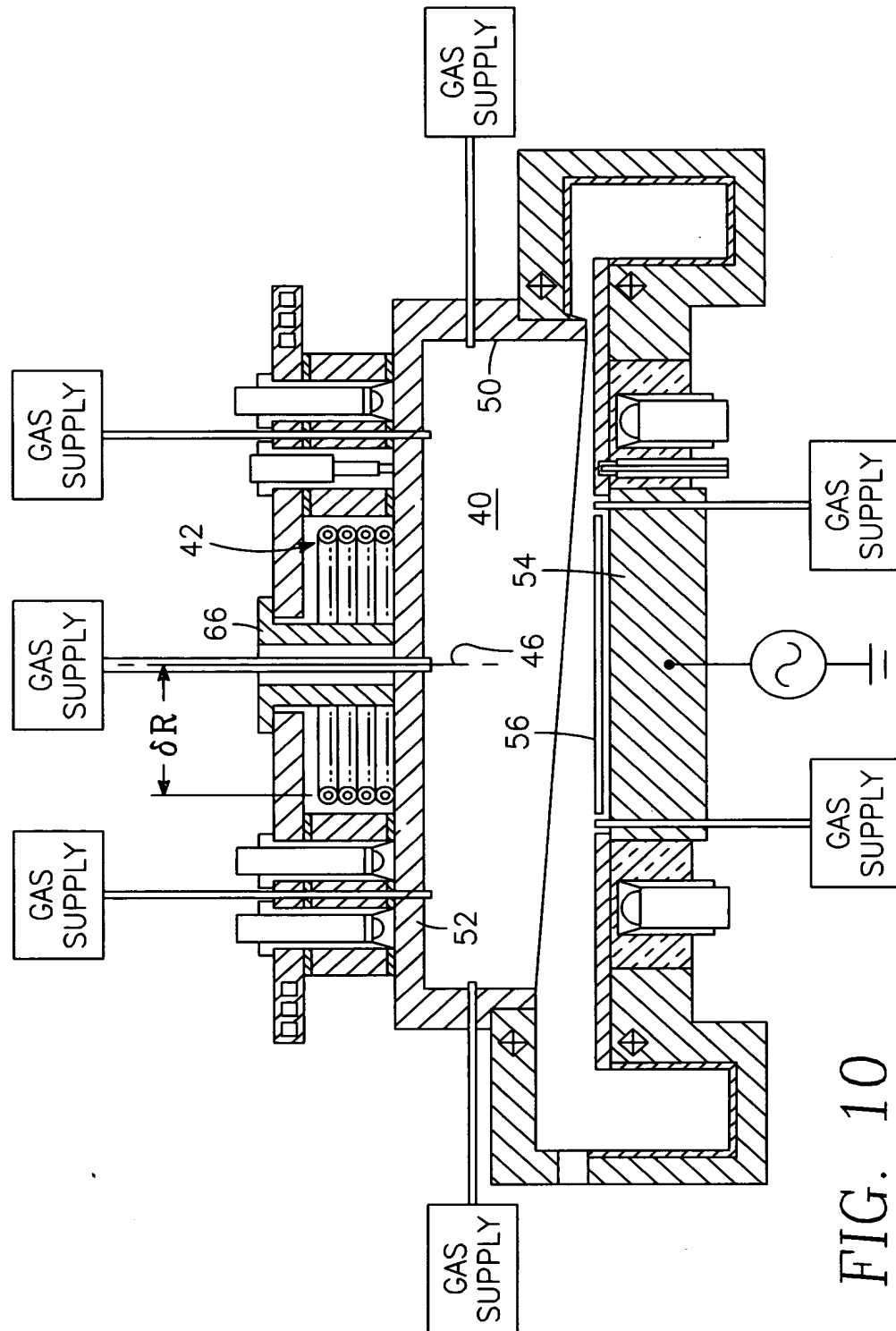
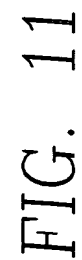


FIG. 10

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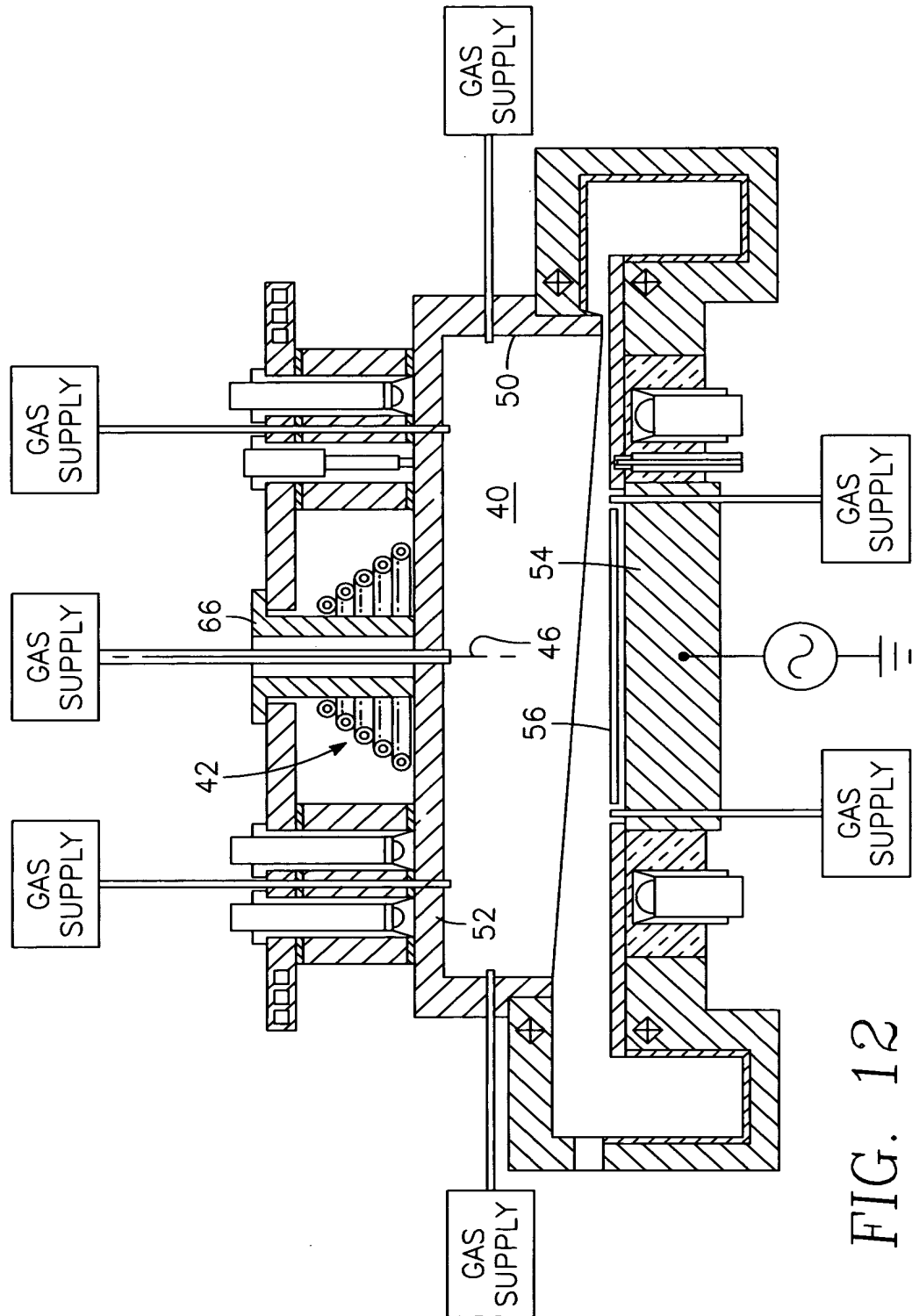


FIG. 12

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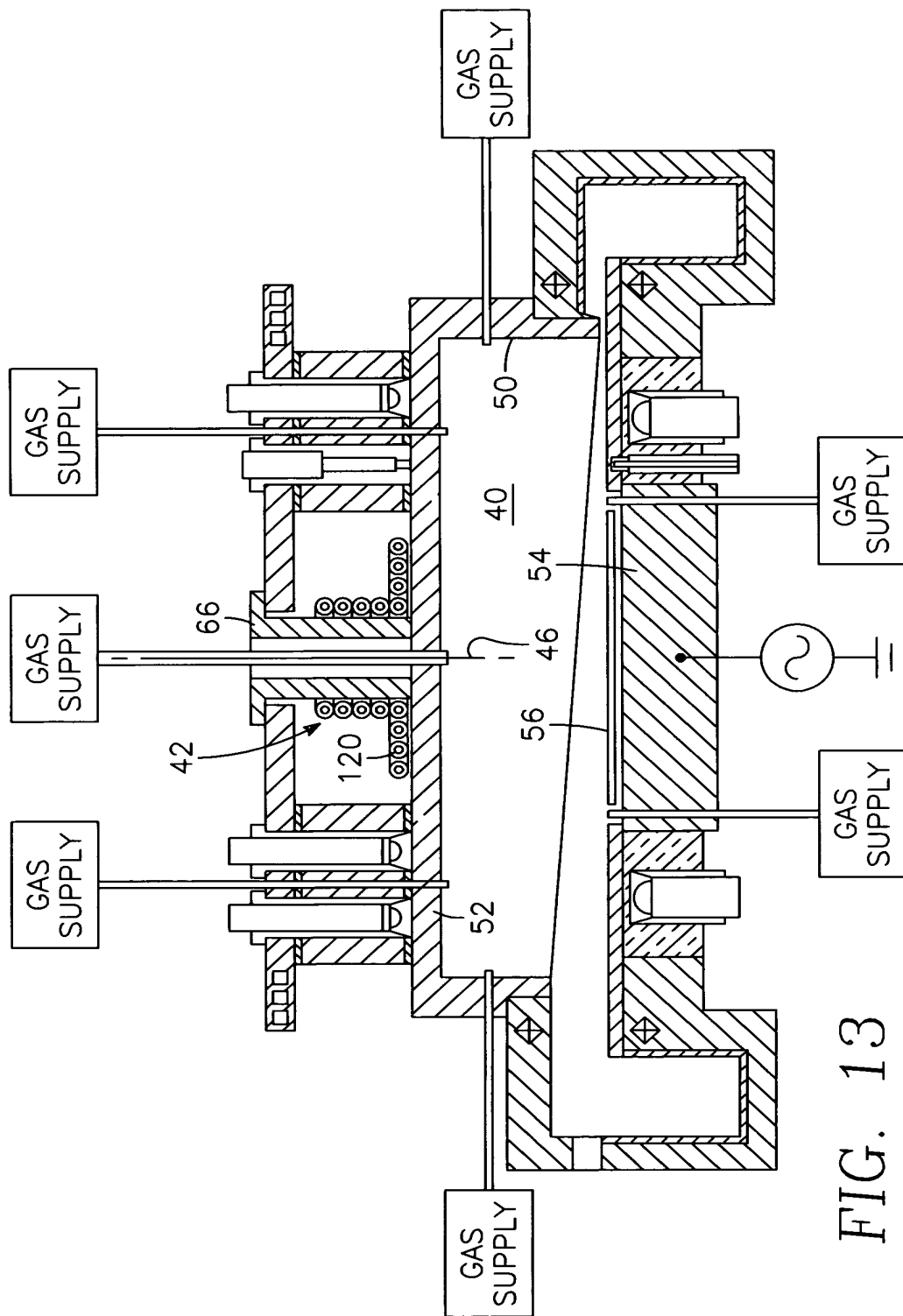
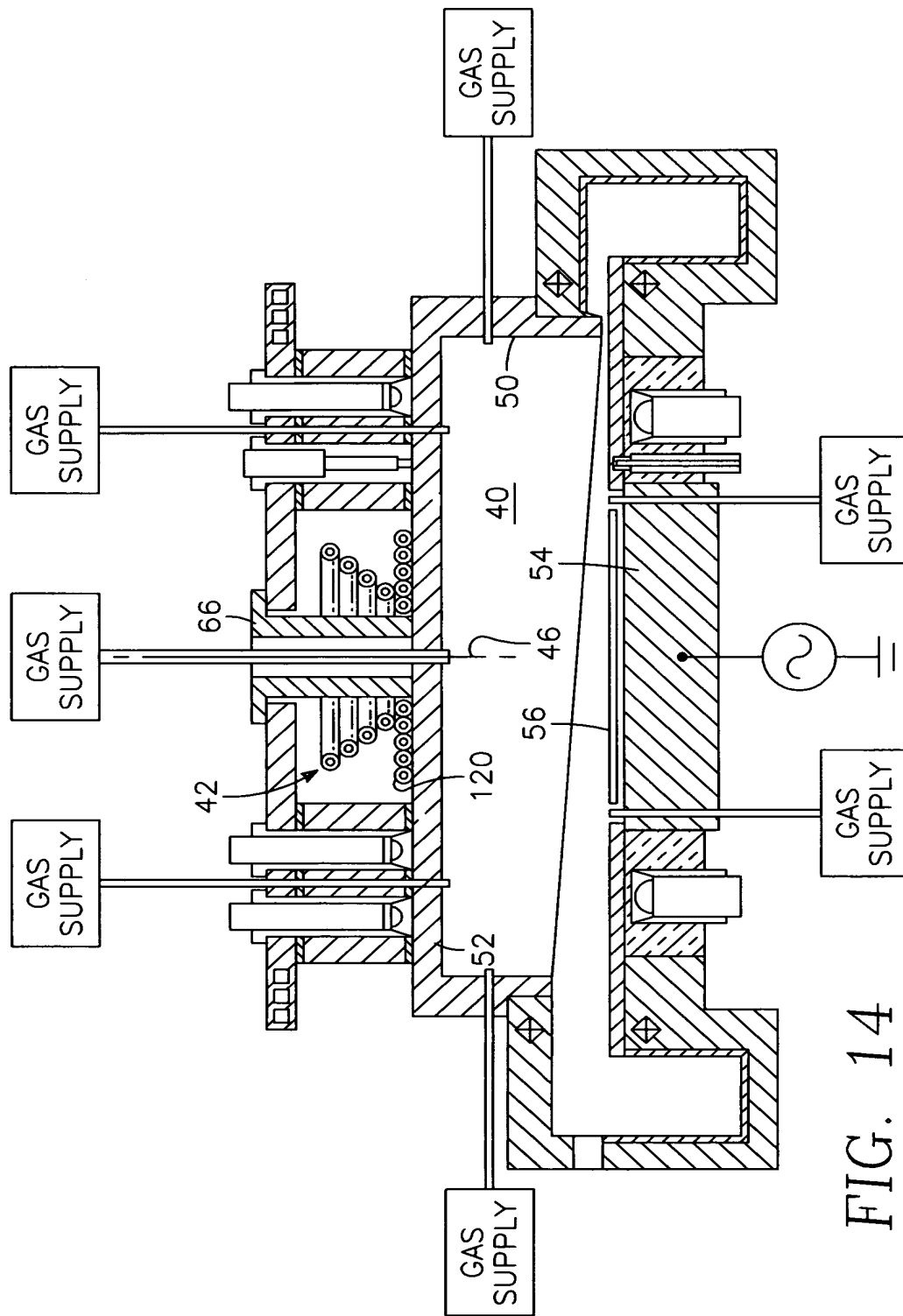


FIG. 13

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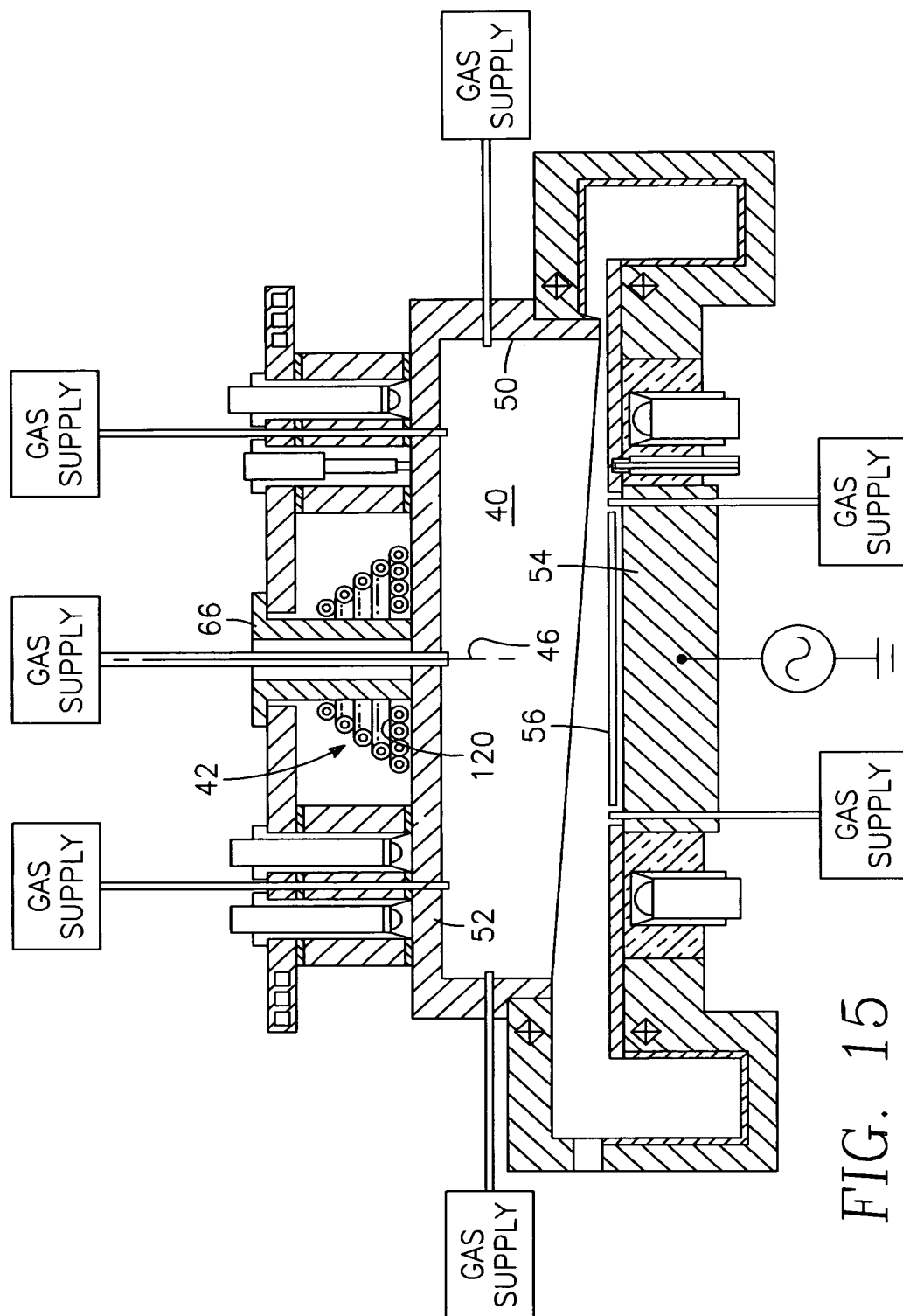


FIG. 15

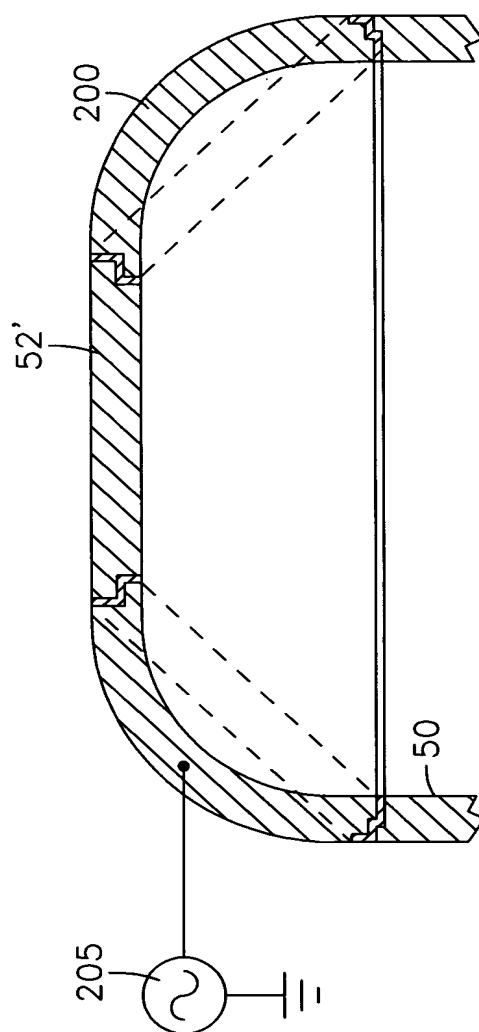


FIG. 16

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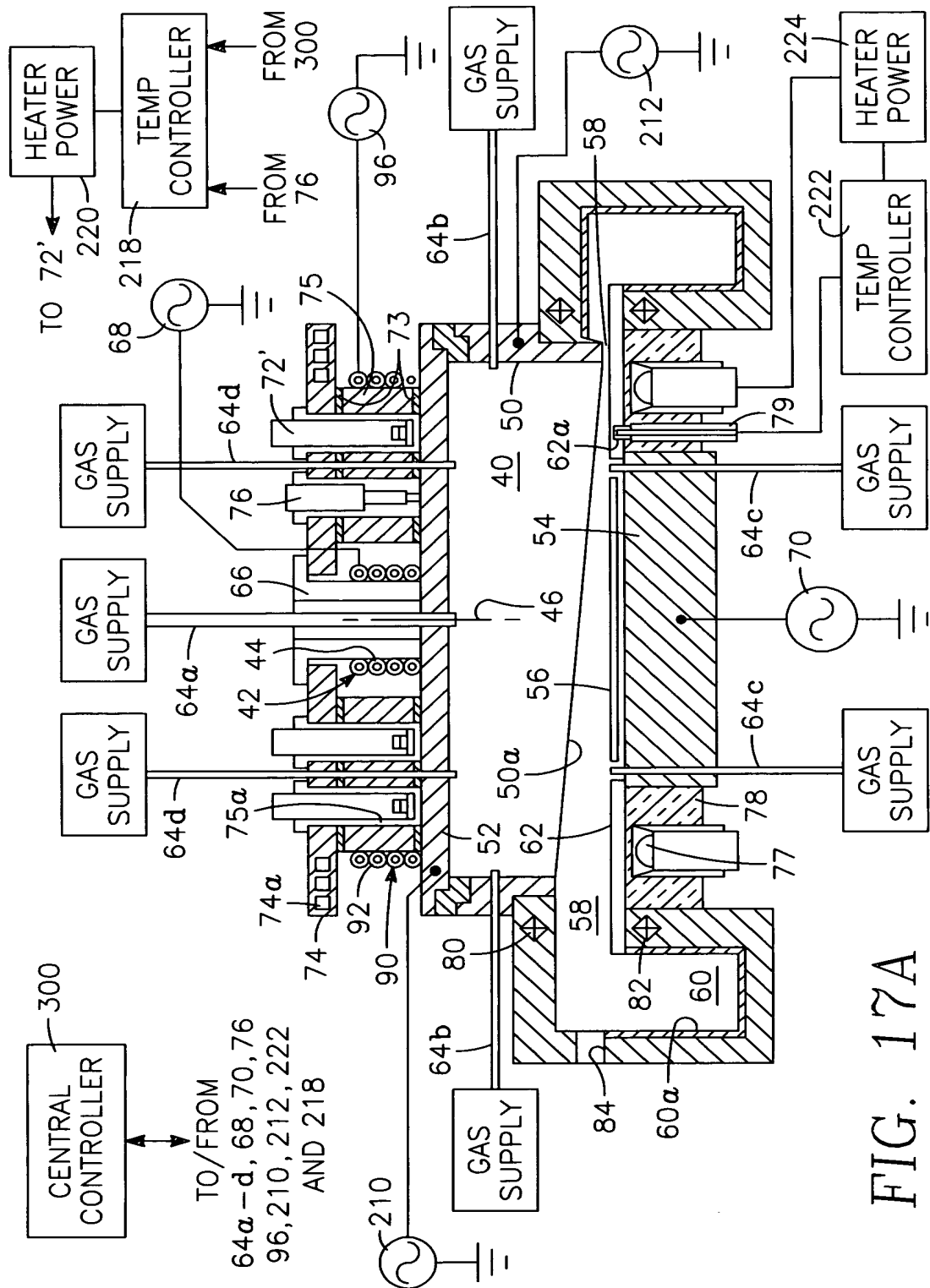


FIG. 17A

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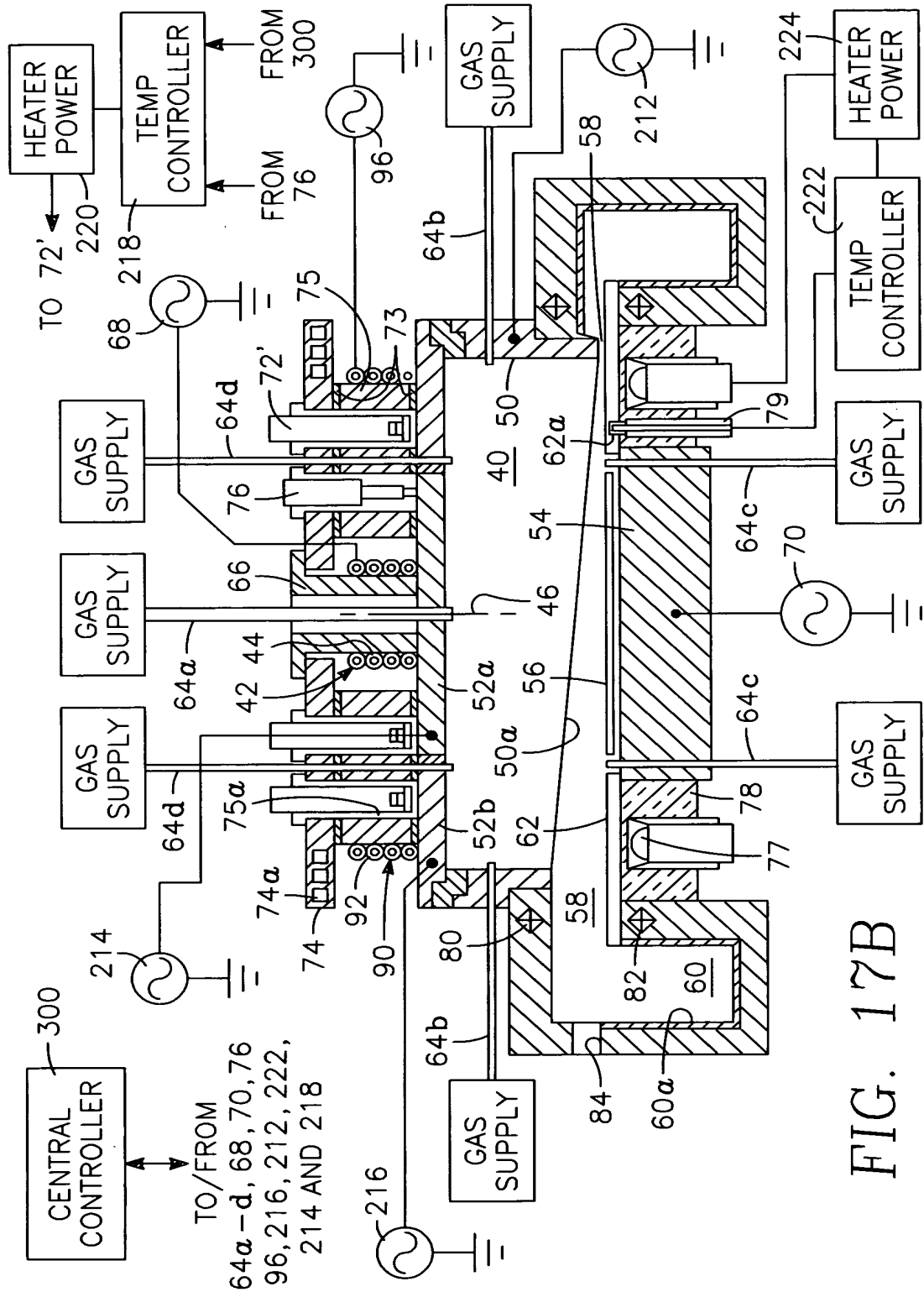


FIG. 17B